

The Development and the commercialization of the Mask Aligner for wafer  
Midas System will continue to grow along with the value creation for our customers.

[www.aligner.co.kr](http://www.aligner.co.kr)

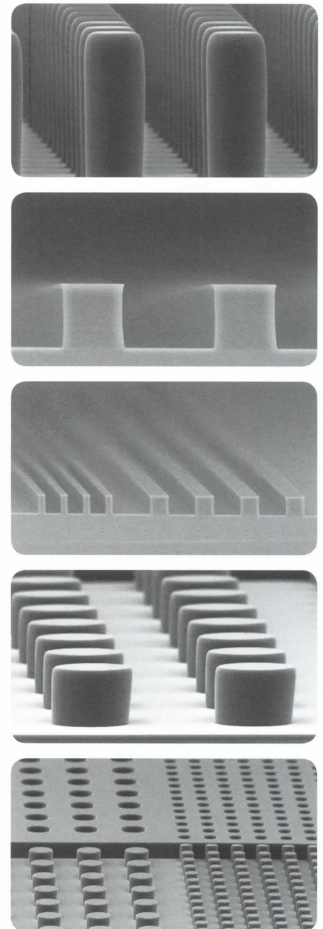
# **MDA-400LJ**



The MDA-400LJ is used for Semiconductor & Application Process. This machine can make a higher Performance of Process. It is ideal, economical unit for University and Research center.



▼ SEM Image



ITEM	SPECIFICATION
Substrate Size	Up to 4 inch
Light source	UV LED
Resolution	1 $\mu$ m with 1 $\mu$ m thin PR @ Si wafer
Alignment Accuracy	$\pm 1\mu$ m
I-line Beam Intensity	About 10mW/cm <sup>2</sup>
Process Mode	Soft, Hard, Vacuum and Proximity